

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
S1	154	gcib gas adj1 cluster adj1 ion adj1 beam "gas cluster ion beam"	US-PGPUB; USPAT; USOCR; EPO; JPO	OR	ON	2005/09/20 08:39
S2	114707	sic silicon adj1 carbide	US-PGPUB; USPAT; USOCR; EPO; JPO	OR	ON	2005/09/20 08:40
S3	45470	mechanical\$3 near2 polish\$4	US-PGPUB; USPAT; USOCR; EPO; JPO	OR	ON	2005/09/20 08:40
S6	29	S1 S2	US-PGPUB; USPAT; USOCR; EPO; JPO	AND	ON	2005/09/20 08:41
S7	154	gcib gas adj1 cluster adj1 ion adj1 beam "gas cluster ion beam"	US-PGPUB; USPAT; USOCR; EPO; JPO	OR	ON	2005/09/20 08:45
S8	114707	sic silicon adj1 carbide	US-PGPUB; USPAT; USOCR; EPO; JPO	OR	ON	2005/09/20 08:45
S9	45470	mechanical\$3 near2 polish\$4	US-PGPUB; USPAT; USOCR; EPO; JPO	OR	ON	2005/09/20 08:45
S10	20	S7 S8 S9	US-PGPUB; USPAT; USOCR; EPO; JPO	AND	ON	2005/09/20 11:13
S11	154	gcib gas adj1 cluster adj1 ion adj1 beam "gas cluster ion beam"	US-PGPUB; USPAT; USOCR; EPO; JPO	OR	ON	2005/09/20 11:13
S12	114707	sic silicon adj1 carbide	US-PGPUB; USPAT; USOCR; EPO; JPO	OR	ON	2005/09/20 11:13
S13	45470	mechanical\$3 near2 polish\$4	US-PGPUB; USPAT; USOCR; EPO; JPO	OR	ON	2005/09/20 11:13
S14	9	S11 S12 not S13	US-PGPUB; USPAT; USOCR; EPO; JPO	AND	ON	2005/09/20 11:13

S15	12775256	(@ad<"20020222" or @rlad<"20020222" or @prad<"20020222")	US-PGPUB; USPAT; USOCR; EPO; JPO	AND	ON	2005/09/21 08:19
S16	160102	"chemical vapor deposition" cvd chemical adj1 vapor adj1 deposition	US-PGPUB; USPAT; USOCR; EPO; JPO	OR	ON	2005/09/21 07:08
S17	154	gcib gas adj1 cluster adj1 ion adj1 beam "gas cluster ion beam"	US-PGPUB; USPAT; USOCR; EPO; JPO	OR	ON	2005/09/21 07:08
S18	114707	sic silicon adj1 carbide	US-PGPUB; USPAT; USOCR; EPO; JPO	OR	ON	2005/09/21 07:08
S19	45470	mechanical\$3 near2 polish\$4	US-PGPUB; USPAT; USOCR; EPO; JPO	OR	ON	2005/09/21 07:08
S20	29	S17 S18	US-PGPUB; USPAT; USOCR; EPO; JPO	AND	ON	2005/09/21 07:08
S21	154	gcib gas adj1 cluster adj1 ion adj1 beam "gas cluster ion beam"	US-PGPUB; USPAT; USOCR; EPO; JPO	OR	ON	2005/09/21 07:08
S22	114707	sic silicon adj1 carbide	US-PGPUB; USPAT; USOCR; EPO; JPO	OR	ON	2005/09/21 07:08
S23	45470	mechanical\$3 near2 polish\$4	US-PGPUB; USPAT; USOCR; EPO; JPO	OR	ON	2005/09/21 07:08
S24	20	S21 S22 S23	US-PGPUB; USPAT; USOCR; EPO; JPO	AND	ON	2005/09/21 07:08
S25	154	gcib gas adj1 cluster adj1 ion adj1 beam "gas cluster ion beam"	US-PGPUB; USPAT; USOCR; EPO; JPO	OR	ON	2005/09/21 07:08
S26	114707	sic silicon adj1 carbide	US-PGPUB; USPAT; USOCR; EPO; JPO	OR	ON	2005/09/21 07:08

S27	45470	mechanical\$3 near2 polish\$4	US-PGPUB; USPAT; USOCR; EPO; JPO	OR	ON	2005/09/21 07:08
S28	9	S25 S26 not S27	US-PGPUB; USPAT; USOCR; EPO; JPO	AND	ON	2005/09/21 07:08
S29	2282	S15 S16 S18 S19 not (S20 or S24 or S28)	US-PGPUB; USPAT; USOCR; EPO; JPO	AND	ON	2005/09/21 08:20
S31	170521	wafer substrate	US-PGPUB; USPAT; USOCR; EPO; JPO	AND	ON	2005/09/21 07:11
S32	1529	S29 S31	US-PGPUB; USPAT; USOCR; EPO; JPO	AND	ON	2005/09/21 07:11
S35	1967548	(@ad>"20020222" or @rlad>"20020222" or @prad>"20020222")	US-PGPUB; USPAT; USOCR; EPO; JPO	AND	ON	2005/09/21 08:19
S36	1220	S35 S16 S18 S19 not (S20 or S24 or S28) S31	US-PGPUB; USPAT; USOCR; EPO; JPO	AND	ON	2005/09/21 08:21